



[10191/1808]

**REPLY UNDER 37 C.F.R. § 1.116
EXPEDITED PROCEDURE
GROUP ART UNIT 1763**

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Inventor(s) : Franz LAERMER et al.
Serial No. : 09/889,838
Filed : January 24, 2002
For : PLASMA ETCHING METHOD HAVING PULSED
SUBSTRATE ELECTRODE POWER
Examiner : Allan Olsen
Art Unit : 1763
Confirmation No. : 1541

Mail Stop AF
Commissioner for Patents
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I hereby certify that this correspondence is being deposited with the United States Postal Service with sufficient postage as first class mail in an envelope addressed to: Mail Stop AF, Commissioner for Patents, P.O. Box 1450, Alexandria, VA 22313-1450 on:

Date: Jan. 20, 2005

Signature: Chili

REPLY UNDER 37 C.F.R. § 1.116

S I R:

In response to the Final Office Action of July 30, 2003, kindly amend the above-captioned application as follows:

Amendments to the Claims are reflected in the listing of claims, which begins on page 2 of this paper.

Remarks begin on page 7 of this paper.

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